

Supporting Information

Modified Vapor Phase Deposition Technology for High-performance Uncooled MIR PbSe Detectors

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Figure S1. Typical FESEM images of modified VPD-PbSe films obtained from various parameters.

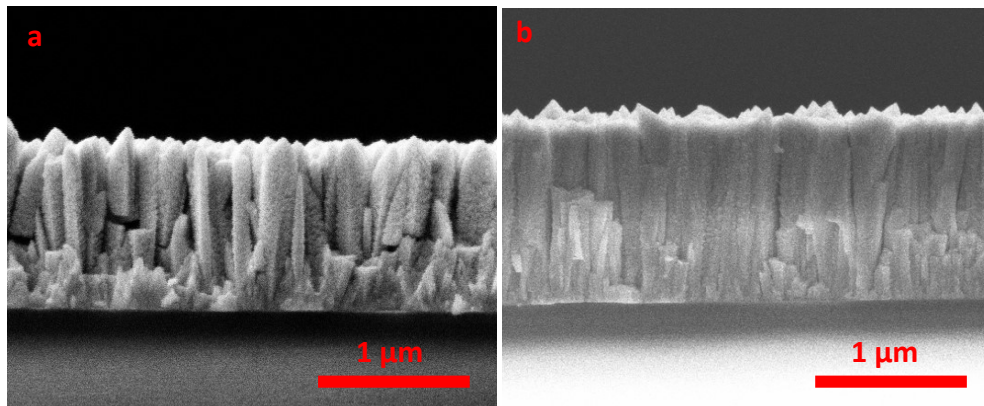


Figure S1 Typical FESEM images of modified VPD-PbSe films obtained from various parameters. (a) 130 °C and 2×10^{-2} Pa O_2 pressure (b) 130 °C and 8×10^{-2} Pa O_2 pressure.